

to govern business proprietary information in this segment of the proceeding. Timely written notification of the return/destruction of APO materials or conversion to judicial protective order is hereby requested. Failure to comply with the regulations and terms of an APO is a violation which is subject to sanction.

These results of administrative review and notice are published in accordance with sections 751(a)(1) and 777(i)(1) of the Act.

Dated: February 23, 2006.

Joseph A. Spetrini,

Acting Assistant Secretary for Import Administration.

[FR Doc. 06-1932 Filed 3-1-06; 8:45 am]

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DEPARTMENT OF COMMERCE

International Trade Administration

Dartmouth College, et al., Notice of Consolidated Decision on Applications, for Duty-Free Entry of Scientific Instruments

This is a decision consolidated pursuant to Section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89-651, 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 a.m. and 5 p.m. in Suite 4100W, Franklin Court Building, U.S. Department of Commerce, 1099 14th Street, NW., Washington, DC. Comments: None received. Decision: Approved. No instrument of equivalent scientific value to the foreign instruments described below, for such purposes as each is intended to be used, is being manufactured in the United States.

Docket Number: 05-047. Applicant: Dartmouth College, Thayer School of Engineering, Hanover, NH. Instrument: Magneto-optic Kerr Effect Microscope. Manufacturer: Durham Magneto Optics, Ltd., UK. Intended Use: See notice at 70 FR 72609, December 6, 2005. Reasons: The foreign instrument provides:

1. Variation of the magnetic field configuration both in time and according to the relative strength of the three directional components.
2. Laser spot size to the order of 1.5 to 2.0 μ m.
3. Ability to rotate the time-varying applied magnetic field relative to the incoming light.
4. Modification of the sensor optics to maximize the signal in order to handle

a variety of sample shapes and thickness.

5. Amenity to instruction of students. Advice received from: The National Institute of Standards and Technology. Docket Number: 05-055. Applicant: Rutgers, The State University of New Jersey, New Brunswick, NJ. Instrument: Near-Field Optical Microscope integrated to Micro-Raman. Manufacturer: Nanonics Imaging Ltd., Israel. Intended Use: See notice at 70 FR 77145, December 29, 2005. Reasons: The foreign instrument is a compatible accessory which is designed to be directly integrated with the applicant's existing Renishaw micro-Raman system. This microscope comes equipped with the Raman software module for the Renishaw Raman and CCD camera spectroscopy control and the Raman low-noise vibration isolation platform. The complete system will meet the applicant's requirements to characterize the chemical bonding and elastic strains in nanostructured materials. Advice received from: The National Institutes of Health. Docket Number: 05-061. Applicant: University of Michigan, Ann Arbor, MI. Instrument: Application Specific Integrated Circuit. Manufacturer: Ideas ASA, Norway. Intended Use: See notice at 71 FR 2024, January 12, 2006. Reasons: The foreign instrument is a compatible accessory for a unique 3-dimensional position sensitive CdZnTe semiconductor gamma-ray spectrometer. The article provides a multi-channel, charge-sensing amplifier with very low noise of about 300 electrons rms, for which three iterations have been developed in collaboration with Ideas ASA. The systems can get energy and 3-D position information for not only single-interaction events, but for multiple-interaction events by using electron drift times. Excellent energy resolution for both single-interaction events (0.8% FWHM at 662 keV) and multiple-interaction events (1.3% FWHM at 662 keV) has been achieved. A new scalable detector array system, with plug-in electronics, is required for further development of the spectrometer. Development of an equivalent device from a different source would cause a significant delay in this project.

Docket Number: 06-001. Applicant: Medical college of Georgia, Augusta, GA. Instrument: Micromanipulator System. Manufacturer: Luigs & Neuman, Germany. Intended Use: See notice at 71 FR 4895, January 30, 2006. Reasons: The foreign instrument is an ancillary device which provides micromanipulator staging and control that will be used to

maneuver electrophysiology equipment, that requires precision in its location, which will be centered around a multi-photon confocal microscope. No known domestic manufacturers produce a micromanipulator system which is compatible with this equipment. Advice received from: The National Institutes of Health.

The capabilities of each of the foreign instruments described above are pertinent to each applicant's intended use of it and we know of no other instrument or apparatus being manufactured in the United States which is of equivalent scientific value to any of the foreign instruments.

Gerald A. Zerdy,

Program Manager, Statutory Import Programs Staff.

[FR Doc. E6-2986 Filed 3-1-06; 8:45 am]

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DEPARTMENT OF COMMERCE

International Trade Administration

Applications for Duty-Free Entry of Scientific Instruments

Pursuant to section 6(c) of the Educational, Scientific and Cultural Materials Importation Act of 1966 (Pub. L. 89-651; 80 Stat. 897; 15 CFR part 301), we invite comments on the question of whether instruments of equivalent scientific value, for the purposes for which the instruments shown below are intended to be used, are being manufactured in the United States.

Comments must comply with 15 CFR 301.5(a)(3) and (4) of the regulations and be filed within 20 days with the Statutory Import Programs Staff, U.S. Department of Commerce, Washington, DC 20230. Applications may be examined between 8:30 a.m. and 5 p.m. in Suite 4100W, U.S. Department of Commerce, Franklin Court Building, 1099 14th Street, NW., Washington, DC. Docket Number: 05-059. Applicant: College of Staten Island, 2800 Victory Blvd., Staten Island, NY 10314. Instrument: Plasma System. Manufacturer: Diener Electronic GmBh & Co., KG, Germany. Intended Use: The instrument is intended to be used to study and develop:

1. Nanotechnology with focused ion beams, including electronic properties of carbon nanowires direct written with nano-scaled ion beams on carbonaceous substrates
2. Micro- and nano-scale light emitting diodes on diamond, with the aim to develop single molecule and single

photon electrically driven light sources operating at room temperature
3. Development of high–pressure, high–temperature diamond anvil cells with internally heated anvils for hydrothermal and shear stress experiments.

The instrument will also be used in courses on materials science. Application accepted by Commissioner of Customs: December 20, 2005.

Docket Number: 06–002. Applicant: The University of Puerto Rico at Mayaguez, Dept. Of Chemistry, Mayaguez, Puerto Rico 00680 Instrument: Electron Microscope, Model JEM–2010 Manufacturer: JEOL Ltd., Japan. Intended Use: The instrument is intended to be used for experimental studies including the characterization of gold and silver nanostructures, structure–property relations in semiconductor nanoparticles, nanowire formations and nanorods, structural fuel cell performance and the catalytic activity of Pt, Ru and Pt–Ru nanostructures, and the structure of functionalized organic–based nanofibers. The instrument will also be used in a variety of courses. Application accepted by Commissioner of Customs: January 20, 2006.

Docket Number: 06–003. Applicant: Oklahoma State University, 203 Whitehurst, Stillwater, OK 74048–3011. Instrument: Electron Microscope, Model JEM–2100F. Manufacturer: JEOL Ltd., Japan. Intended Use: The instrument is intended to be used for studies including:

1. Decomposed metal complexes at low temperatures which yield nanocrystalline products that are useful catalysts, electrode materials for batteries and supercapacitors, corrosion inhibitors, photovoltaics, and sorbants for pollutants.
2. Semiconducting nanoparticles (as small as 2 nm), single wall nanotubes and the electrical conductivity of either a semiconductor or a metal, depending on the diameter and helicity of the tube.
3. Virus–vector interactions in several important plant disease inducing viruses, that are vectored by fungi, for understanding emerging diseases in plants.

It will also be used for graduate student training in electron microscopy. Application accepted by Commissioner of Customs: January 23, 2006. Docket Number: 06–004. Applicant: University of North Texas, Department of Materials Science and Engineering,

3940 N. Elm, Research Park Room E132, Denton, TX 76203. Instrument: Mass Spectrometer, Model Nova 200 NanoLab. Manufacturer: FEI Company, The Netherlands. Intended Use: The instrument is intended to be used in a central research facility for studies in materials science, chemistry, biology and physics. For example, in materials science and engineering, it will be used to study shape–memory metallic alloys, aluminum alloys for automotive uses, porous ceramic thin films and strained Si substrates for microelectronic devices, polymer nanocomposites, characterization of ion beam–solid interaction, optoelectronic thin films for solid state lighting and photovoltaic applications, and ceramic materials for low temperature solid oxide fuel cells. Application accepted by Commissioner of Customs: February 14, 2006.

Docket Number: 06–005. Applicant: University of Maryland, Materials Science and Engineering Department, Kim Building, Room 1237, College Park, MD 20742. Instrument: Electron Microscope, Model JEM–2100F. Manufacturer: JEOL Ltd., Japan. Intended Use: The instrument is intended to be used to characterize nanomaterials and nanocomposites at the atomic level. These include semiconductor nanostructures, polymeric materials, metal nanoparticles, ferroelectric/ferromagnetic oxide nanocomposites and semiconductor nanowires. Properties of materials examined include crystal structure and quality of material, structural defects, and morphology using techniques of electron diffraction, high resolution lattice imaging, bright/dark field imaging and obtaining electron diffraction patterns and images of areas as small as a few nanometers in diameter. The instrument will also be used in courses and for conducting individual graduate research projects. Application accepted by Commissioner of Customs: February 8, 2006.

Gerald A. Zerdy,

Program Manager, Statutory Import Programs Staff.

[FR Doc. E6–2988 Filed 3–1–06; 8:45 am]

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DEPARTMENT OF COMMERCE

International Trade Administration

Villanova University, et al., Notice of Consolidated Decision on Applications, for Duty–Free Entry of Electron Microscopes

This is a decision consolidated pursuant to section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89–651, 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 a.m. and 5 p.m. in Suite 4100W, Franklin Court Building, U.S. Department of Commerce, 1099 14th Street, NW., Washington, DC.

Docket Number: 05–058. Applicant: Villanova University, Villanova, Pa. Instrument: Electron Microscope, Model H–7600–2 TEM. Manufacturer: Hitachi High–Technologies Corp., Japan. Intended Use: See notice at 71 FR 4895, January 30, 2006. Order Date: February 23, 2005.

Docket Number: 05–062. Applicant: University of Texas Medical Branch at Galveston, Galveston, TX. Instrument: Electron Microscope, Model JEM–2200FS. Manufacturer: JEOL Ltd., Japan. Intended Use: See notice at 71 FR 2024, January 12, 2006. Order Date: February 23, 2005.

Comments: None received. Decision: Approved. No instrument of equivalent scientific value to the foreign instrument, for such purposes as these instruments are intended to be used, was being manufactured in the United States at the time the instruments were ordered. Reasons: Each foreign instrument is a conventional transmission electron microscope (CTEM) and is intended for research or scientific educational uses requiring a CTEM. We know of no CTEM, or any other instrument suited to these purposes, which was being manufactured in the United States either at the time of order of each instrument OR at the time of receipt of application by U.S. Customs and Border Protection.

Gerald A. Zerdy,

Program Manager, Statutory Import Programs Staff.

[FR Doc. E6–2987 Filed 3–1–06; 8:45 am]

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